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E UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: OZAKI, Takashi, et al.

Group Art Unit: 2813

Serial No.: 10/517,765

Examiner: MCCALL SHEPARD, Sony

Filed: February 3, 2006

P.T.O. Confirmation No.: 6791

FOR: SUBSTRATE TREATING APPARATUS AND METHOD FOR MANUFACTURING

SEMICONDUCTOR DEVICE

## **AMENDMENT AFTER ALLOWANCE UNDER 37 C.F.R. 1.312**

## **MAIL STOP AF**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

April 13, 2010

Sir:

Applicants received a Notice of Allowance dated **January 28, 2010** in connection with the above-identified application. It is respectfully requested that the following amendment be made to the claims of this application:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.